

Notice of References Cited	Application/Control No. 10/789,736		Applicant(s)/Patent Under Reexamination YIN ET AL.	
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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,841,341	01-2005	Fairbairn et al.	430/323
*	B	US-2004/0092098	05-2004	Sudijono et al.	438/637
*	C	US-2003/0198814	10-2003	Khieu et al.	428/412
*	D	US-5,830,332	11-1998	Babich et al.	204/192.15
*	E	US-6,795,636	09-2004	Cronk et al.	385/141
*	F	US-5,470,661	11-1995	Bailey et al.	428/408
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
	U	Lide, David R., ed., <i>CRC Handbook of Chemistry and Physics, Internet Version 2005</i> , http://www.hbcnetbase.com , CRC Press, Boca Raton, FL, 2005, pg. 12-157.			
	V	He <i>et al.</i> , Characterization and optical properties of diamondlike carbon prepared by electron cyclotron resonance plasma, <i>J. Mater. Res.</i> , 14(3) (Mar 1999) 1055.			
	W	Zhou <i>et al.</i> , Deposition and properties of a-C:H films on polymethyl methacrylate by electron cyclotron resonance microwave plasma chemical vapor deposition method, <i>Surface and Coatings Technology</i> , 123 (2000) 273.			
	X	Chen <i>et al.</i> , Optical constants of tetrahedral amorphous carbon films in the infrared region and at a wavelength of 633 nm, <i>J. Appl. Phys.</i> , 87(9) (May 2000) 4268.			

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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